

DUAL MEMBRANE PIEZOELECTRIC MICROELECTROMECHANICAL SYSTEM MICROPHONE

ABSTRACT

5 A piezoelectric microelectromechanical system microphone comprises a piezoelectric
element configured to deform and generate an electrical potential responsive to impingement
of sound waves on the piezoelectric microelectromechanical system microphone, a sensing
electrode disposed on the piezoelectric element and configured to sense the electrical
potential, and a passive membrane mechanically coupled to the surface of the piezoelectric
10 element to increase sensitivity of the piezoelectric microelectromechanical system
microphone.

[FIG. 1A]

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